

Technology Development of LGADs at FBK

Fondazione Bruno Kessler

G. Borghi, M. Boscardin, M. Centis Vignali¹, F. Ficarella, O. Hammad Ali, G. Paternoster

University of Trento and TIFPA

G.F. Dalla Betta, L. Pancheri

University of Torino and INFN

R. Arcidiacono, N. Cartiglia, M. Mandurriano, V. Monaco, M. Ferrero, S. Giordanengo,
F. Siviero, V. Sola, M. Tornago, A. Vignati

Paul Scherrer Institute

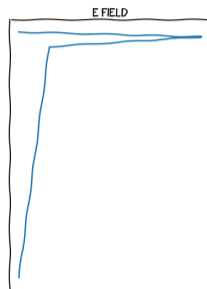
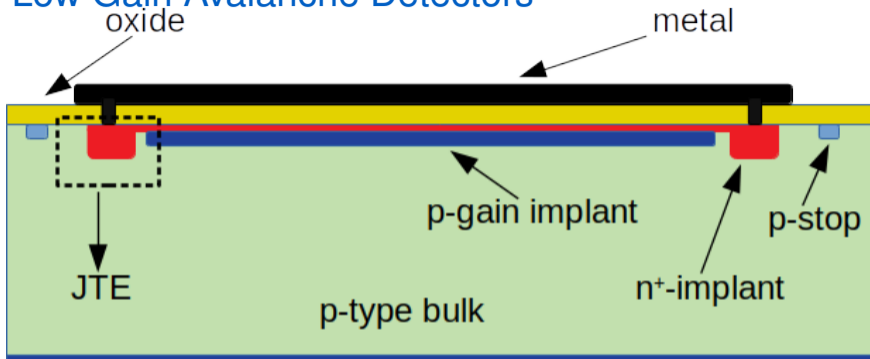
M. Andrae, A. Bergamaschi, B. Schmitt, J. Zhang

18/02/2020 TREDI 2020



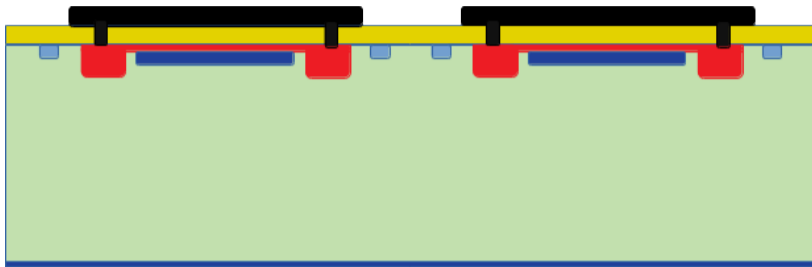
¹mcentisvignali@fbk.eu

Low Gain Avalanche Detectors



- Silicon detectors with charge multiplication
- Gain ≈ 10
- Gain layer provides high-field region
- Junction Termination Extension improves stability

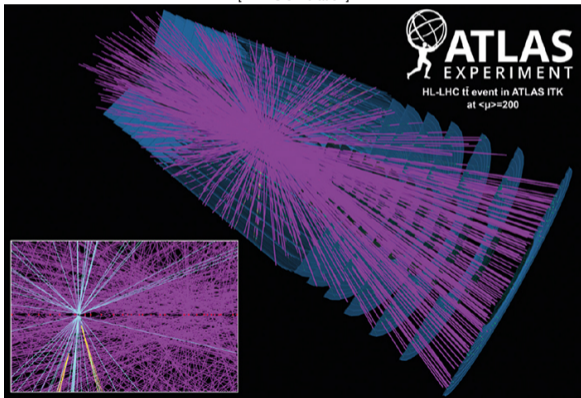
- **Improve SNR of the system**
(When the sensor shot noise is not dominating)
- Noise and power consumption
 \Rightarrow low gain



- LGAD structure is repeated
- No-gain area between channels
- JTE and channel isolation contribute to the no-gain area

HL-LHC: With the current vertex resolution a significant fraction of the vertices will not be resolved

[ATLAS simulation]



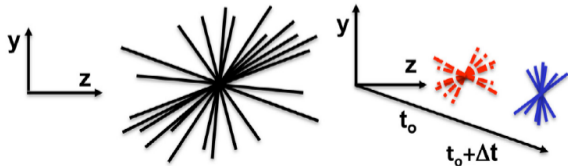
Development within the UFSD project



Use time coordinate to mitigate pile-up

- Track time resolution ≈ 30 ps
- Radiation resistance to few 10^{15} n_{eq}/cm^2
- Hit time resolution at end of life ≈ 50 ps

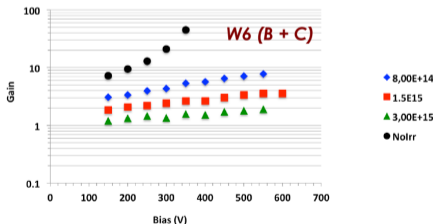
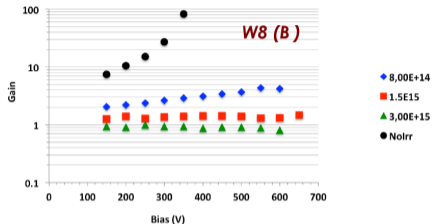
[H. Sadrozinski et al. 2018 Rep. Prog. Phys. 81 026101]



Radiation Hardening of LGADs

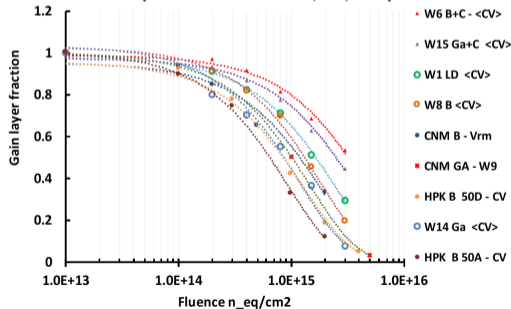
[R. Arcidiacono TREDI2018]

$$\text{Gain} = Q(\text{LGAD}) / Q(\text{PiN})$$



- Thin sensors
- Mult. layer affected by acceptor removal
- Modify the mult. layer doping profile
- Use of different dopants to reduce the effect (Ga, C co-implantation)

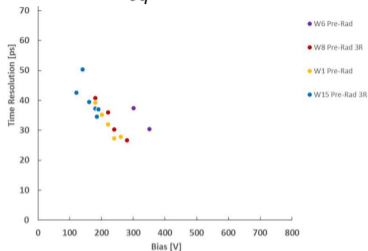
[M. Ferrero et al. NIM A 919 (2019) 16-26]



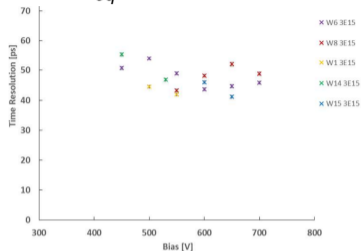
Carbon co-implantation makes the gain layer more radiation hard

LGADs for Timing

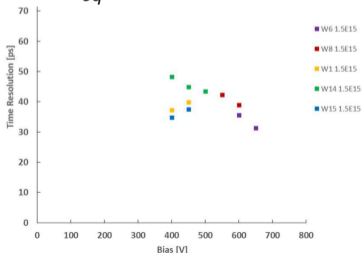
$$\Phi_{eq} = 0 \text{ cm}^{-2}$$



$$\Phi_{eq} = 3 \cdot 10^{15} \text{ cm}^{-2}$$



$$\Phi_{eq} = 1.5 \cdot 10^{15} \text{ cm}^{-2}$$

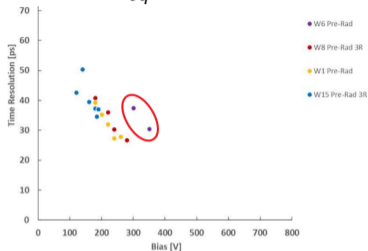


- Thickness of 50-60 μm \Rightarrow support wafer
- Measurements using charged particles
- **Reached required time resolution up to $\Phi_{eq} = 3 \cdot 10^{15} \text{ cm}^{-2}$**
- C coimplantation (W6): improved time resolution up to $\Phi_{eq} = 1.5 \cdot 10^{15} \text{ cm}^{-2}$

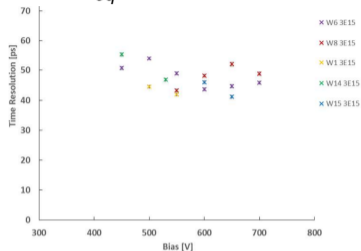
[S. Mazza arXiv 2018]

LGADs for Timing

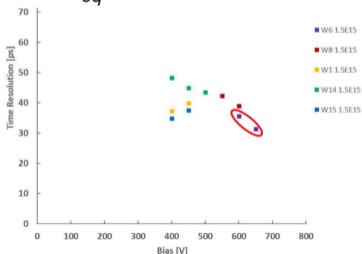
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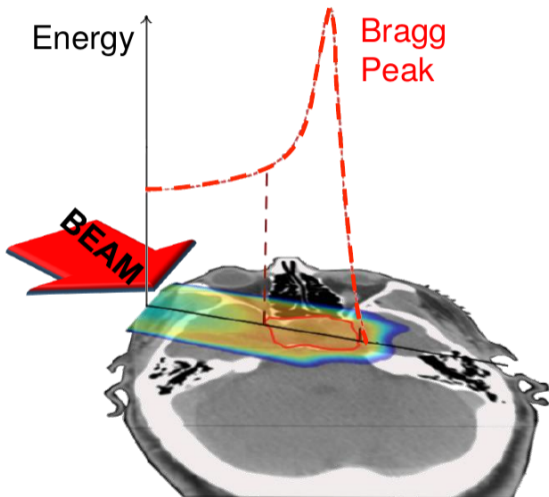
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[S. Mazza arXiv 2018]

A. Vignati [Picosecond Workshop 2018]



Development within the MoVeIT project

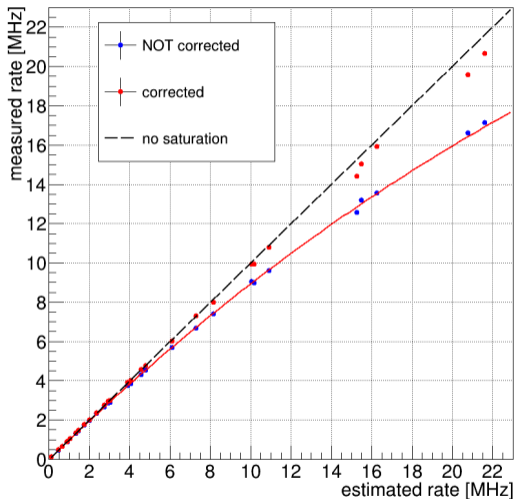


Beam monitoring during treatment

- Quality assurance
- Energy (TOF measurement)
- Particle count
- Beam profile

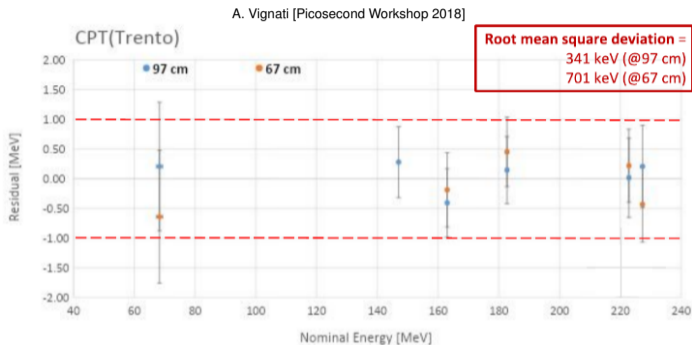
Sensor requirements similar to HEP **but** TOF measurement using several particles

A. Vignati [MMND 2020]



- LGAD strip sensor
- Rate on one strip
- Goal rate: 1-2 MHz/strip
- Pile-up correction with paralizable model extends linearity

Particle counting accuracy meets expectations



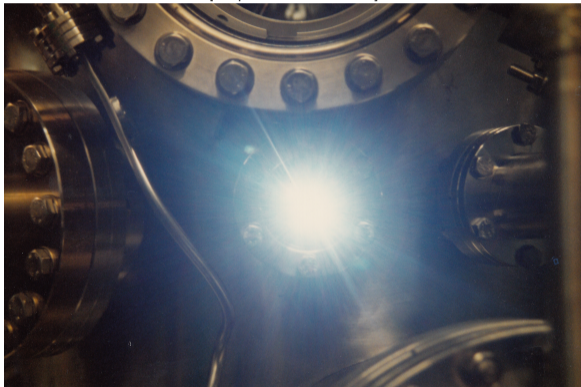
- LGAD strip sensor
- TOF measurement
- L = 67, 97 cm

Energy resolution meets expectations

Production for full scale prototype will start soon



[Wikipedia CC BY-SA 2.0]



Detection of soft X-rays: 250 eV - 2 keV

- K-edges of bio elements
→ pharmaceuticals, cell imaging
- L-edges of 3d-transition metals
→ magnets, superconductors, quantum materials ...

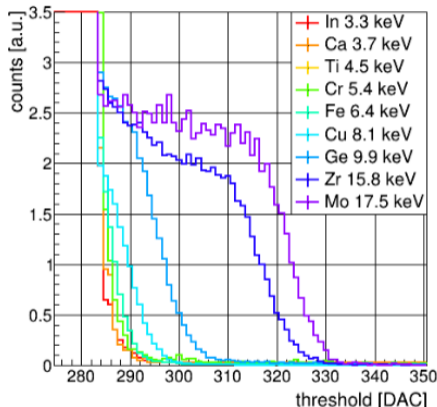
Use LGADs:

- Gain to lower the detection limit of photon counting detectors
- Gain to improve SNR of integrating detectors
- Thin entrance window must be developed

Low Energy X-ray Detection

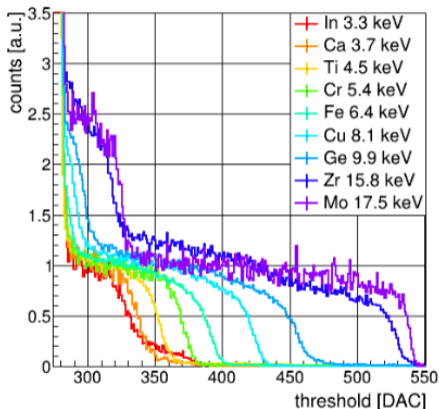
Photon counting strip detectors, fluorescence X-rays

PiN sensor (zoomed)



$E > 8$ keV visible

LGAD sensor



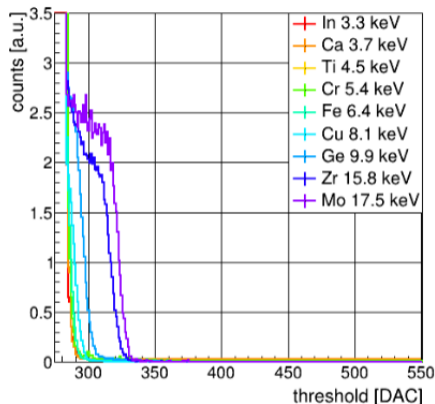
$E < 3.3$ keV visible

Improvement in detection threshold

Low Energy X-ray Detection

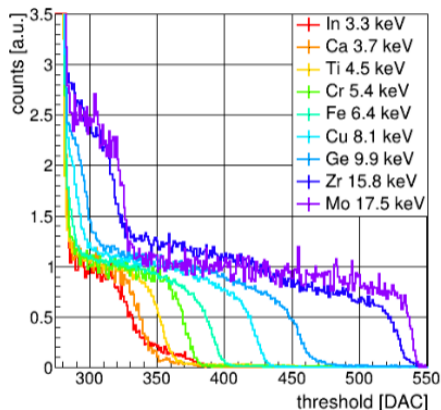
Photon counting strip detectors, fluorescence X-rays

PiN sensor



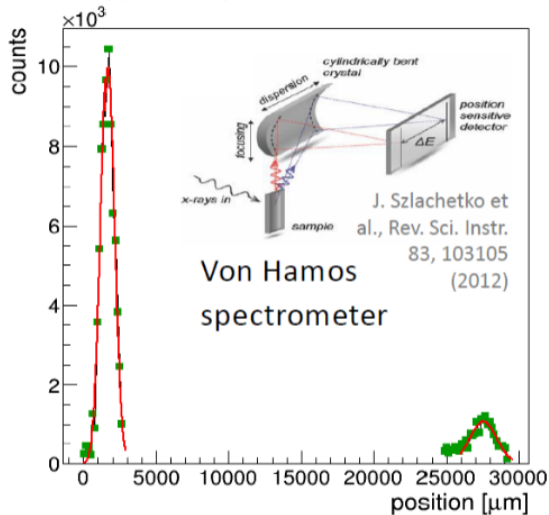
$E > 8$ keV visible

LGAD sensor



$E < 3.3$ keV visible

Improvement in detection threshold

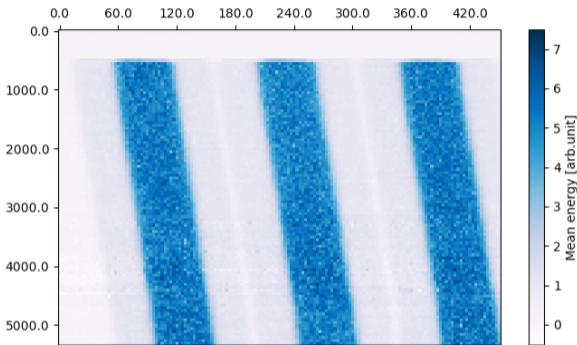


Detection of 2.31 keV photons

- Photon counting LGAD strip detector
- Fluorescence X-rays
- Sulfur target
- $K_{\alpha} = 2.31$ keV
- $K_{\beta} = 2.46$ keV
- Von Hamos spectrometer

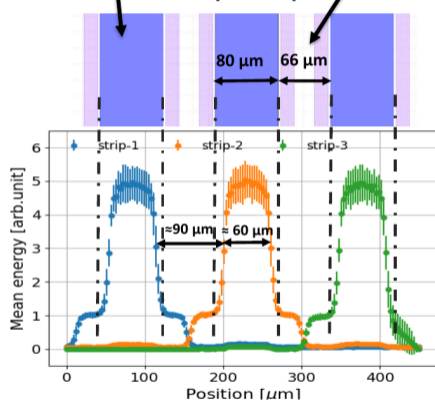
Segmentation: Fill Factor

Focused 20 keV x-ray beam



- Measured FF: $\approx 40\%$
- Impact on detection efficiency

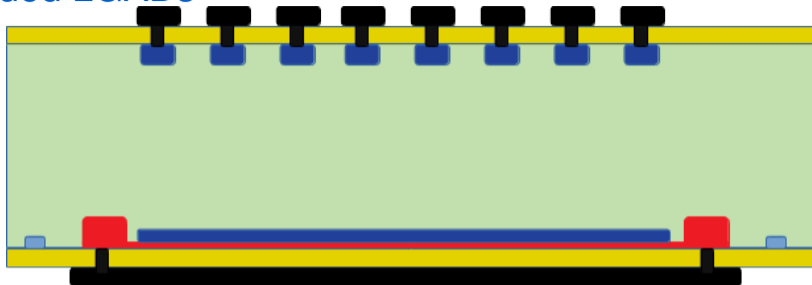
Nominal Gain region
Inter-strip border
146 μm strips



Signal vs position for 3 strips

Fill factor needs improvement

Double Sided LGADs



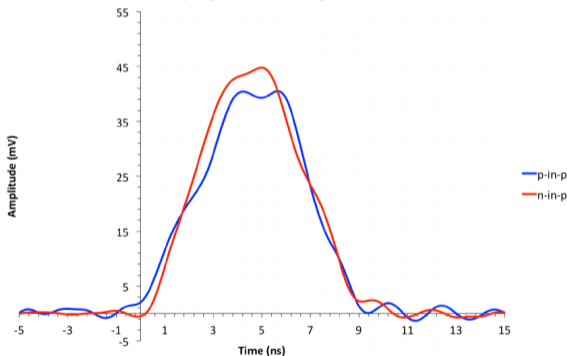
- Continuous gain area in the active region \Rightarrow 100% fill factor
- Double sided process
- Active thickness is the wafer thickness
- Readout side is ohmic
- Design not optimal for timing applications
- Readout side separated from LGAD side \Rightarrow no restrictions on channel dimensions

[G.F. Dalla Betta et al. NIM A 796 (2015) 154]

[M. Ferrero 29th RD50 Workshop 2016]

p-in-p Vs n-in-p signals

p-segmentation Vs n-segmentation



Proof of concept in first FBK LGAD production

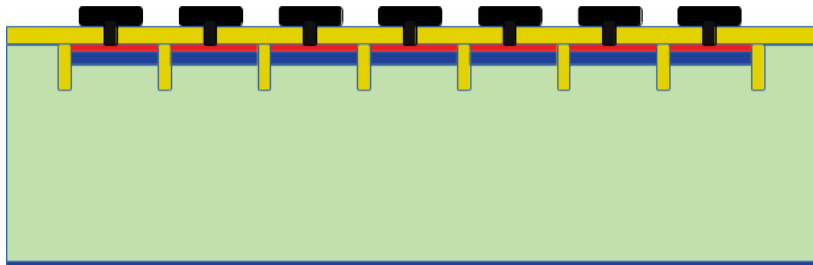
- Signal of regular vs double sided LGAD
 - Pad size \gg thickness
 - Laser illumination
 - Signals are similar
 - A difference is expected for smaller pads
-
- Production to start soon dedicated to X-ray detection
 - Optimization for thin entrance window (LGAD side)

AC Coupled LGADs



- Continuous gain area in the active region \Rightarrow 100% fill factor
- Readout channels capacitively coupled
- Resistive layer to limit signal spreading
- No restrictions on channel dimension
- One production optimized for timing \Rightarrow results in N. Cartiglia talk (this session)
- One future production to start in summer 2020



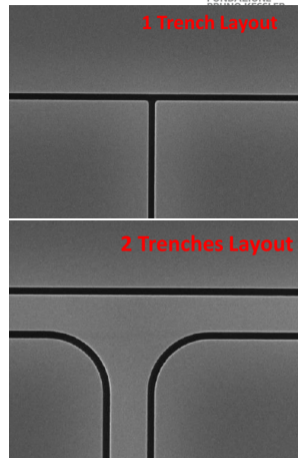
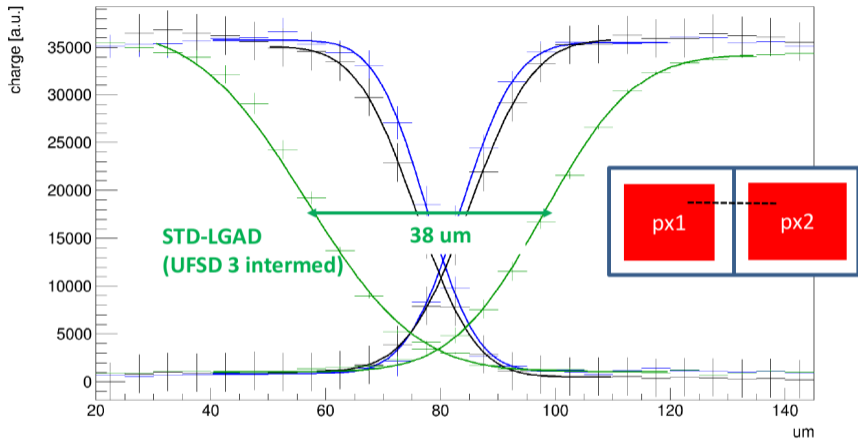


- Trenches substitute the JTE and isolation structures
- Trench width about $1 \mu\text{m}$ \Rightarrow fill factor close to 100%
- One production optimized for timing

[G. Paternoster et al. IEEE EDL (2019) in revision]

Trench Isolated LGADs

Laser characterization



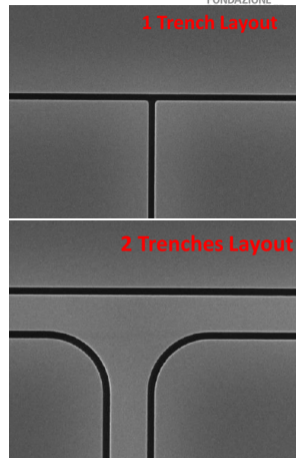
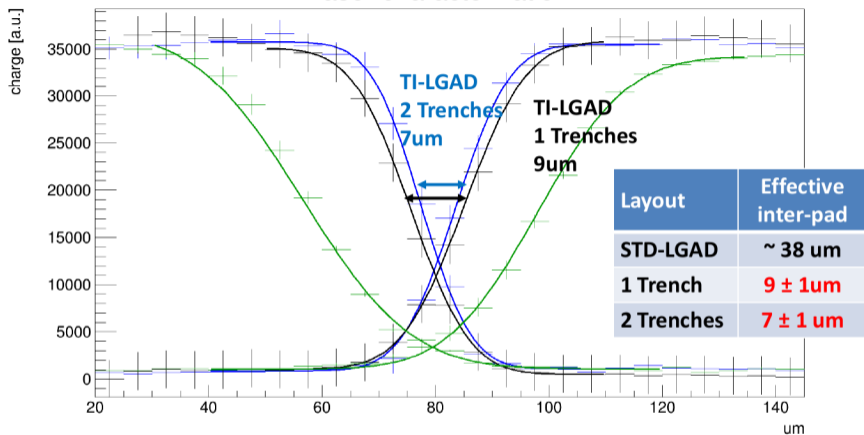
Factor 5 reduction in no-gain area

Production optimized for timing to start soon



Trench Isolated LGADs

Laser characterization



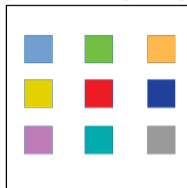
Factor 5 reduction in no-gain area

Production optimized for timing to start soon

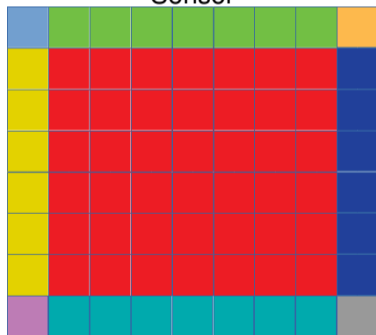


Process Capabilities

Recticle $\approx 2 \times 2 \text{ cm}^2$ on wafer



Sensor



Stitching

- Stepper machine to reduce min feature size with respect to mask aligner
- Recticle constraints the sensor size
- Stitching overcomes this limitation

Tested successfully in one LGAD production

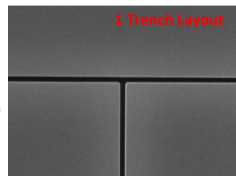
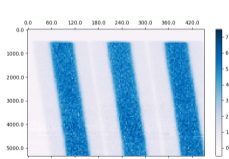
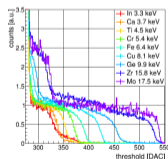
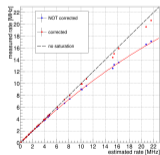
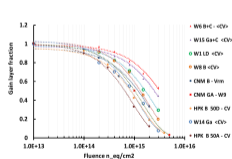
[G. Paternoster TREDI2019]

Wafer thinning

- Handle wafer ($\approx 300 \mu\text{m}$) used in production of thin ($\approx 50 \mu\text{m}$) LGADs
- Material budget constraints in several application
- Thinning to reduce handle wafer thickness

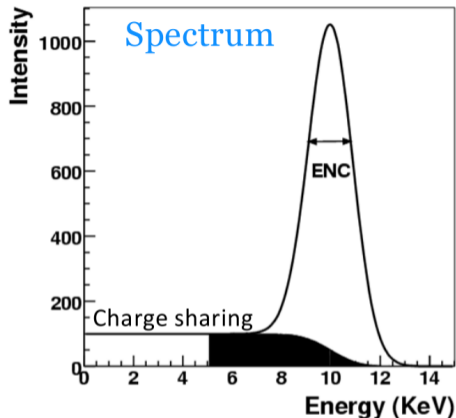
Capability to be acquired in the next 1.5 years

- Active development of LGADs at FBK
- Several projects benefit from the sensors
- Development and evolution of different LGAD “flavors” to solve different measurement problems
- Several LGAD productions foreseen in the future

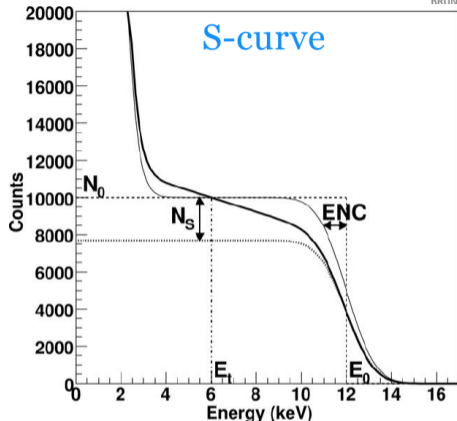


Backup Material

Photon Counting Detectors Characterization



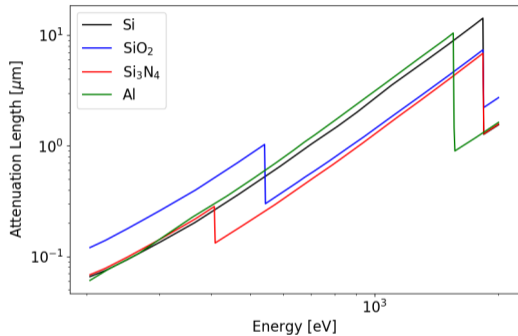
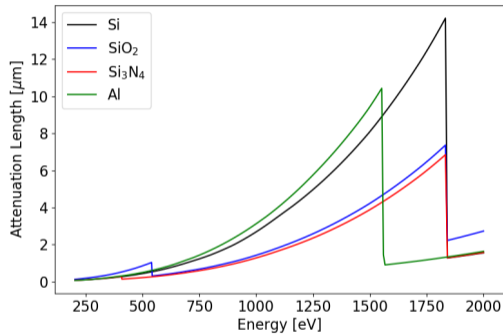
- Monochromatic x-rays
- Can be fluorescence



- S-curve by scanning the threshold
- S-curve is the running integral of the spectrum

[A. Bergamaschi TREDI2019]

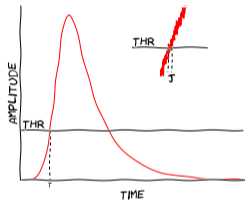
X-ray Attenuation Length



http://henke.lbl.gov/optical_constants/atten2.html

$$\sigma_t^2 = \sigma_{\text{jitter}}^2 + \sigma_{\text{time walk}}^2 + \sigma_{\text{Landau noise}}^2 + \sigma_{\text{distortion}}^2 + \sigma_{\text{TDC}}^2$$

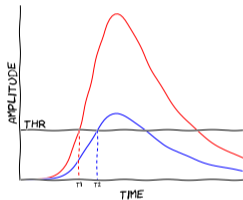
Jitter



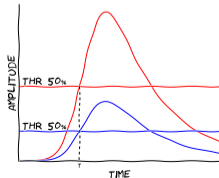
$$\sigma_{\text{jitter}} = \sigma_n / \frac{dV}{dt}$$

Increase $\frac{dV}{dt}$, SNR

Time walk



Correct for it, e.g. CFD

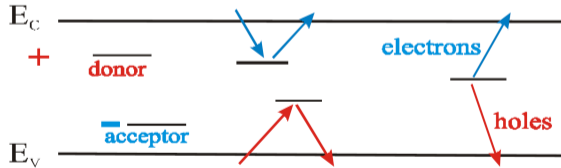


- Landau noise: non-uniformity in the energy deposited per unit length
- Distortion: change in signal shape due to detector non-uniformities
- TDC: resolution of the TDC, if no other effects: $\text{bin}/\sqrt{12}$

Radiation Damage in Silicon Detectors

Bulk damage

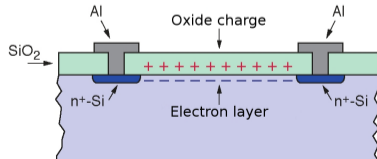
- Non ionizing energy loss (NIEL)
- Defect generation in the lattice
- Change of V_{dep}
- Increase in leakage current
→ noise
- Decrease in signal



Damage expressed as
equivalent fluence of 1 MeV neutrons Φ_{eq} [cm^{-2}]

Surface damage

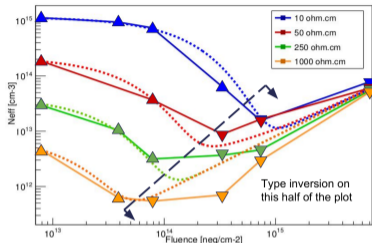
- Ionizing energy loss in SiO_2
- Traps at the Si- SiO_2 interface
- Build up of positive charge
- Modification of electric field
→ charge losses
→ noise
→ breakdown
- Conductive layers
- Affects sensors and electronics



Relevant quantity: dose in SiO_2

Change in doping in boron-doped p-type silicon

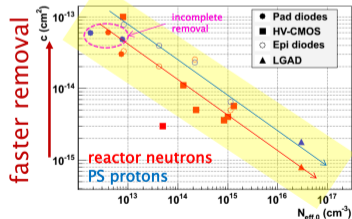
[P. de Almeida, TREDI2018]



Affects:

- p-type silicon sensors
- LGADs → gain reduction
- CMOS sensors → change in depletion region

[G. Kramberger, HSTD11 2017]



$$N_{eff}(\Phi) = N_{eff}(0) - N_c(1 - e^{-c\Phi}) + g_c\Phi$$

N_{eff} → effective doping concentration

N_c → “removable” dopants

c → acceptor removal constant

Φ → fluence

g_c → introduction rate